

Title (en)

APPARATUS FOR VACUUM DEPOSITION, SPECIFICALLY FOR METALLIZING PLASTIC FILM

Title (de)

VORRICHTUNG ZUR VAKUUMBESCHICHTUNG, INSBESONDERE ZUM METALLISIEREN VON KUNSTSTOFFOLIEN

Title (fr)

APPAREIL DE DEPOT SOUS VIDE DESTINE, EN PARTICULIER, A LA METALLISATION D'UN FILM PLASTIQUE

Publication

EP 1440178 A1 20040728 (EN)

Application

EP 02788542 A 20021029

Priority

- IT 0200687 W 20021029
- IT FI20010205 A 20011102

Abstract (en)

[origin: WO03038142A1] The apparatus comprise a vacuum chamber (3) inside which a feeding device of the substrate (F) and a bank (25) of vaporization sources are arranged. The substrate feeding device can be extracted from the vacuum chamber. Conversely, the vaporization source bank can be raised from a lower vaporization position to a higher maintenance position without needing to be extracted from said vacuum chamber.

IPC 1-7

C23C 14/56; **C23C 14/24**

IPC 8 full level

C23C 14/24 (2006.01); **C23C 14/56** (2006.01)

CPC (source: EP)

C23C 14/246 (2013.01); **C23C 14/562** (2013.01)

Citation (search report)

See references of WO 03038142A1

Cited by

US6427491B1

Designated contracting state (EPC)

AT BE BG CH CY CZ DE DK EE ES FI FR GB GR IE IT LI LU MC NL PT SE SK TR

DOCDB simple family (publication)

WO 03038142 A1 20030508; EP 1440178 A1 20040728; IT FI20010205 A1 20030502

DOCDB simple family (application)

IT 0200687 W 20021029; EP 02788542 A 20021029; IT FI20010205 A 20011102